



In the United States Patent and Trademark Office

Inventor: Aratani et al.

Serial No.: 09/429,719

Title: Thin Film Formation Use ...

Atty. Docket No. 9792486-0100

Examiner: R. McDonald

Group Unit: 1753

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Response "D" to First Non-Final Office Action After RCE Filing

In response to the Office Action dated 25 Oct. 2001, the applicants respond as follows.

A. In the Claims, please amend as follows:

Please cancel claims 1, 7, 10-12, 14-16 and add new claims 17-24.

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17. (New) A method of forming a thin film comprising the step of: forming an AgPd alloy thin film using a sputtering target material, the AgPd alloy thin film comprising Pd in an amount ranging from 0.5 to 4.9 atomic % and Cu in an amount ranging from 0.1 to 3.5 atomic %; and irradiating an information recording layer with a light beam having a wavelength.

18. (New) The method of claim 17, wherein the thin film has a thickness from approximately 500 Angstroms to approximately 1500 Angstroms.

~~19. (New) The method of claim 17, wherein the wavelength is less than or equal to 650 nm.~~

20. (New) The method of claim 17, wherein the thin film has a thickness from approximately 500 Angstroms to approximately 1500 Angstroms; and wherein the wavelength is less than or equal to 650 nm.